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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Group Art Unit 2877

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In re application of : February 14, 2002

Ausschnitt et al. : Examiner:

Serial No. 10/035,061 : IBM Corporation

Dept. 18G/Bldg. 300-482
2070 Route 52,
Hopewell Junction,
New York 12533-6531

Filed: December 28, 2001 :

Title: PHASE SHIFTED TEST
PATTERN FOR MONITORING FOCUS
AND ABERRATIONS IN OPTICAL
PROJECTION SYSTEMS

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REQUEST FOR CORRECTION OF OFFICIAL FILING RECEIPT

Commissioner of Patents
Washington, D.C. 20231

Sir:

Upon receiving the filing receipt (attached) for the above-captioned patent application, it was noted that one of the inventors names was incorrect. The name should be: CHRISTOPHER P. AUSSCHNITT. In addition, the assignee's city should be corrected to read ARMONK.

No fee is believed to be necessary.

Respectfully submitted,

By: Todd M. C. Li

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TML/kcm



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APPLICATION NUMBER	FILING DATE	GRP ART UNIT	FIL FEE REC'D	ATTY.DOCKET.NO	DRAWINGS	TOT CLAIMS	IND CLAIMS
10/035,061	12/28/2001	2877	824	FIS9-2001-0254 us1	12	20	4

CONFIRMATION NO. 3269

FILING RECEIPT



Todd M. C. Li
IBM Corporation-Zip 482
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Date Mailed: 02/01/2002

AW 29

Receipt is acknowledged of this nonprovisional Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Customer Service Center. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

Applicant(s)

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Assignment For Published Patent Application

INTERNATIONAL BUSINESS MACHINES CORPORATION, aRMONK, NY;

Domestic Priority data as claimed by applicant

Foreign Applications

If Required, Foreign Filing License Granted 02/01/2002

Projected Publication Date: 07/03/2003

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Early Publication Request: No

Title

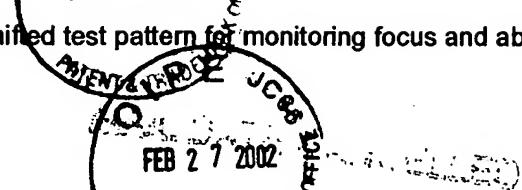
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1450 4 01 2
FEB 28 2002
Phase shifted test pattern for monitoring focus and aberrations in optical projection systems

Preliminary Class

356

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